- **Arrayed Waveguide Grating with Reusable**
- 2 Delay Lines (RDL-AWG) for High Resolving
- **Power, Highly Compact, Photonic**
- 4 Spectrographs
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12 Abstract: An innovative arrayed waveguide grating with reusable delay lines (RDL-AWG) 13 was designed and experimentally demonstrated as a high resolving power integrated photonic 14 spectrometer. An array of directional couplers is optimized to distribute the input signal from 15 the delay lines into the free propagation region. This design is >100 times more compact than 16 the traditional AWGs. By making the AWGs more compact, it significantly reduces the impact 17 of fabrication imperfections and uniformity issues which prevent traditional AWGs from 18 achieving ultra-high resolving powers. A resolving power of 95,000 was recently measured in 19 an RDL-AWG with a footprint of 4.2 x 2.9 mm<sup>2</sup> and no phase compensation. © 2022 Optica 20 Publishing Group under the terms of the Optica Publishing Group Open Access Publishing 21 Agreement

# 22 1. Introduction

23 Arrayed waveguide gratings have been extensively used in optical communication as 24 wavelength routers, multiwavelength receivers, multiwavelength lasers, wavelength-selective 25 switches and add-drop multiplexers [1]. They will also find applications in on-chip spectral-26 domain optical coherence tomography [2], optical sensors [3], neural networks [4], quantum 27 information and astronomy. Astrophotonic spectrograph is an emerging field geared towards 28 bringing the advantages of photonic integrated circuits (PICs) to astronomical 29 spectroscopy [5,6]. These on-chip spectrographs can be made compatible with established CMOS processes and have demonstrated good performances in terms of throughput, spectral 30 31 resolving power, polarization control, etc.

Among various implementations of photonic spectrographs, arrayed waveguide grating (AWG) is one of the most promising technologies, as it is relatively simpler in design and easier in fabrication [7–9]. The high efficiency of AWGs makes it more suitable for astrophotonic spectroscopy, and potentially as building blocks for cascaded structures. Multi-stage AWG and micro-ring resonator integrated AWG designs have also been studied for expanding the resolving power of a singular AWG [10–13].

38 However, as the resolving power ( $R = \lambda / \Delta \lambda$ , where  $\Delta \lambda$  is 3-dB transmission bandwidth) increases, the footprint of the traditional AWG design increases monotonically, 39 40 which incorporates two free propagation regions (FPRs) and an array of waveguides. The phase 41 errors caused by fabrication variations are proportional to the device footprint, which leads to 42 a degradation in device performance as the AWG resolving power increases [14,15]. Various 43 approaches have been studied to reduce the impact of phase-error issues, including footprint 44 reduction and active phase compensation [16,17]. When the number of arrayed waveguides 45 increases to over 100, which is necessary for high resolving powers (R > 10,000), the active 46 phase control requires complex digital circuits and high power consumption. The footprint reduction is typically achieved by overlapping the input and output FPRs or adding reflectors
to the ends of the arrayed waveguides [18,19]. Either way could only reduce the footprint by a
maximum factor of 2. Here, we introduce an innovative approach to design a much more
compact AWG with reusable delay lines (RDL-AWG), which uses only one waveguide to bring
accurate power and phase distributions into the output FPR.

52 The paper is organized as follows. In the following section, we will first briefly discuss the 53 motivation for the RDL-AWG development and in Section 3, the theoretical design rules of 54 RDL-AWGs will be provided. In Section 4, we will provide the details of the fabrication 55 process of the device and the measurement set-up. The performance of fabricated devices will 56 be analyzed in Section 5. Finally, the outlook towards future development and conclusions will 57 be given in Section 6.

# 58 2. Motivation for RDL-AWG development

59 In a traditional AWG, the arrayed waveguides between two FPRs are constructed to introduce 60 a constant path difference between adjacent waveguides. The longest waveguide is at least  $\lambda$ . 61 R, where  $\lambda$  is the operating wavelength and R is the resolving power [20]. This implies that to 62 achieve a higher resolving power AWG spectrometer requires an increase in the optical path 63 length of the arrayed waveguides. Not only does this result in an increase of the footprint of the 64 device, but also, more importantly, it leads to optical phase errors that are generated by 65 fabrication imperfections which can become a significant issue [14,15]. These phase errors 66 degrade the performance of the device by deteriorating the shape of the peaks, and therefore, 67 increase insertion loss and cross-talk, and limit the resolving power [21,22]. To alleviate this 68 issue, active corrections of waveguide phase errors based on integrating electro-optic or 69 thermo-optic phase shifters in high-R AWGs are typically used [17,23]. However, 70 incorporating a phase shifter into every waveguide of the device would significantly increase 71 the size, weight, power consumption, and cost (Swap-C) of the device. It also brings complexity 72 to the chip fabrication and the testing of the AWG.

73 To break the ultimate limitation in achieving high-R, we present an AWG with reusable 74 delay lines, see Fig. 1. Unlike the traditional AWGs, where the phase distribution is introduced 75 by an array of waveguides with different lengths between two FPRs, one single waveguide is 76 used to provide both the power and phase distribution by an array of embedded directional 77 couplers (DCs). The transmitted power and phase of each DC in the array is controlled by both 78 the gap width and the coupling length. With the capability to fabricate sub-10 nm feature size 79 by electron-beam (E-beam) lithography, the arrayed DCs can generate arbitrary power and 80 phase distribution required to illuminate the output FPR. In this paper, to prove the concept, a 81 power and phase distribution that are the same as the traditional AWG are generated by the 82 arrayed DCs. The footprint of the spectrometer is reduced by a factor of more than 100. It eliminates the need for making large AWGs and the associated step of actively compensating 83 84 the phase error.



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Fig. 1 A schematic of the arrayed waveguide grating with reusable delay lines (RDL-AWG).

# 88 3. Theoretical design of RDL-AWG

89 The design flow of the embedded array of DCs is shown in Fig. 2 (a). The purpose of the arrayed 90 DCs is to generate the power and phase distribution that feed into the FPR shown in Fig. 1. 91 Both the required power and phase distribution presented in this work are the same as those of 92 the output FPR in the traditional AWG. A traditional AWG is simulated by Rsoft to get the 93 proper phase distribution. The power distribution is simply a Gaussian distribution, while the 94 phase distribution can be treated as an array of 0's at the central wavelength  $\lambda_0$ . For the other 95 wavelengths, the phase is a linear distribution depending on the grating orders. The power and 96 phase look-up table of the DCs is simulated by the Beam Propagation Method in Rsoft, and further modified by experimental data. It contains the values of  $\beta$ ,  $\theta_1$ ,  $\theta_2$  for different coupling 97 98 lengths L, as shown in Fig. 2 (b), where  $\beta$  is the remaining power coefficient,  $\theta_1$  is the extra 99 phase introduced in the bus of the DC,  $\theta_2$  is the extra phase introduced in the coupler of the DC. 100 In this work, the gap width of the DC is 0.6 um. Then, the two databases are used to calculate 101 the lists of coupler length L and extra path P, shown in Fig. 2 (a), where the extra path P is used 102 to correct the phase distribution caused by  $\theta_1$  and  $\theta_2$ . To demonstrate how we use the lists of L 103 and P to construct the new AWG structure, two examples of the implementations are shown.

104 The optical path difference  $\Delta L$  is set by the grating order m ( $\Delta L = m \times \lambda_0$ ), which is directly 105 related to the resolving power (R) by  $R \approx m \times N$ , where N is the number of waveguides in the 106 array. After the calculation of the L and P lists, to change the R value, the only parameter that 107 needs to be changed is  $\Delta L$ . This makes the design process simple and fast. We note that by 108 adjusting both the phase and the power distribution of the light in the waveguides, we can 109 generate different input profiles. For example, a flat-top transmission profile for each of the 110 output channels can be achieved by altering the power distribution [20,24].



Power and phase simulated in a directional coupler.

117 A model is established to accurately measure the parameters  $\beta$ ,  $\theta_1$ ,  $\theta_2$ , which is based on 118 the Mach–Zehnder interferometer (MZI), as shown in Fig. 3 (a). A MZI constructed with two 119 identical 2×2 multi-mode interferometers (MMIs) is designed as the baseline structure to 120 extract the  $\alpha$  that is the property of the MMIs. It also works as a reference to eliminate any extra 121 losses, like propagation loss, fiber-waveguide coupling loss, etc. In Fig. 3 (b), one directional 122 coupler with coupling length L is added to the upper arm of the MZI. The rest of the test 123 structure is the same as the baseline structure. This ensures that there is no extra phase or power 124 disturbance in the MZI. By measuring the output power  $P_{DC}$ , we can extract the value of  $\beta$ , 125 based on the equation,

$$P_{DC} = P_{in} \cdot \alpha_1 \cdot (1 - \beta)$$

(1)

127 Fig. 3 (c) shows the extracted  $1 - \beta$  as a function of coupler length L. Then,  $\theta_1$  can be 128 evaluated for a measured P<sub>MZI</sub>, based on the equation,

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$$P_{MZI} = P_{in} \cdot \alpha_1 \cdot \alpha_2 \cdot \left| \left( \sqrt{\beta} \cdot e^{j(\theta_1 + \phi)} + e^{j\phi} \right) \right|^2$$
(2)

Fig. 3 (d) shows the extracted  $\theta_1$  as a function of coupler length L. Finally,  $\theta_2$  can be extracted by fitting  $\theta_1$  as a function of coupling length L in the theory.



Fig. 3 (a) Baseline structure to extract  $\alpha$ . (b) Test structure to extract  $\beta$ ,  $\theta_1$ . (c)  $(1-\beta)$  as a 139 function of coupler length L. (d) Phase shift in bus  $\theta_1$  as a function of coupler length L.

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Table 1	1 Summary	of the	design	specs o	f the two	RDL-AV	VGs
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	RDL-AWG #1	RDL-AWG #2
Waveguide cross-section	$1.0 \ \mu m  imes 0.3 \ \mu m$	$1.0 \ \mu m  imes 0.3 \ \mu m$
Number of waveguides	20	20
Grating order	1600	8000
FSR @1550 nm	0.91 nm	0.182 nm
$\Delta L$	1637.372 μm	8186.860 µm
Number of outputs	8	8
Targeted resolving power	30,000	120,000
Minimum radius of curvature	60 µm	60 µm
Footprint	$0.9 \times 2.9 \text{ mm}^2$	$4.2 \times 2.9 \text{ mm}^2$

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142 In this paper, two RDL-AWG designs based on the above calculations are generated, as 143 shown in Fig. 4 (a), with targeted resolving power of 30,000 and 120,000, respectively. We will 144 refer to the two designs as RDL-AWG #1 and RDL-AWG #2 in the following content. The 145 design specs are summarized in Table. 1. As proof-of-concept RDL-AWGs, the number of 146 arrayed waveguides is 20 for both designs, and the number of the output channels is chosen to 147 be 8. While the current proof-of-concept design has a limited free spectral range (FSR), the 148 design easily allows more arrayed waveguides and output channels to be added to increase the 149 FSR. The footprints of the devices are  $0.9 \times 2.9 \text{ mm}^2$  and  $4.2 \times 2.9 \text{ mm}^2$ , respectively. The 150 footprints of the devices are reduced by more than 100 times compared to the traditional AWGs, 151 as shown in Fig. 4 (b). It is worth mentioning that we are comparing the footprint of RDL-AWGs and traditional AWGs with the same number of arrayed waveguides and grating orders, 152 153 with the same thickness of Si<sub>3</sub>N<sub>4</sub>.





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Fig. 4 (a) Two RDL-AWG designs with targeted resolving power of 30,000 and 120,000, respectively. (b) The comparison between the RDL-AWGs and traditional AWGs. The purple ones are the RDL-AWGs. The red ones are the traditional AWGs.

#### 160 4. Fabrication and measurement

161 The PIC was fabricated on a  $Si_3N_4/SiO_2$  on silicon platform, which provides benefits such as 162 low optical losses, transparency over a wide wavelength range (400-2350 nm), compatibility 163 with CMOS, and wafer-scale foundry processes. The structure used in this paper has layers of 164 10-um thermal SiO<sub>2</sub> as the bottom cladding, 300-nm Si<sub>3</sub>N<sub>4</sub> deposited by low pressure chemical

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165 vapor deposition (LPCVD) as the core layer, and 3-um SiO<sub>2</sub> deposited by plasma enhanced 166 chemical vapor deposition (PECVD) as the top cladding. Compared to thinner Si<sub>3</sub>N<sub>4</sub> films, this 167 geometry has lower bending losses in waveguides with small radii of curvature (for a 60-um-168 radius bend, the bending loss is 0.37 dB/m), which allows us to design ultra-compact RDL-169 AWGs. The RDL-AWG design was patterned by a 100 keV Elionix ELS-G100 e-beam system. 170 A 10-nm Cr film was deposited as the mask to etch the 300-nm Si<sub>3</sub>N<sub>4</sub> layer. Compared to the 171 traditional AWGs, the process of etching is more critical in RDL-AWGs, as the transmitted 172 power and phase of the directional couplers are sensitive to the etching depth and quality 173 (sidewall roughness). To achieve the expected power and phase distribution to the output FPR, 174 the etching rate needs to be carefully calibrated.

175 The setup to characterize the transmission response of the RDL-AWGs is shown in Fig. 5. 176 A polarization maintaining tunable laser source (Keysight, 81607A) operating over a 177 wavelength range of 1450 nm - 1640 nm was used, which has a narrow linewidth (0.1 pm) and 178 a high signal to total source spontaneous emission ratio (>70 dB). A polarization maintaining 179 single mode fiber (PM1550) with a typical mode-field diameter of 10.1 µm and a numerical 180 aperture of 0.125 was used to carry the signal from the tunable laser source to the RDL-AWG 181 and out to the power meter. The polarization of the signal entering the RDL-AWG was 182 controlled by a high precision fiber rotator (Thorlabs, HFR007). The fibers were butt-coupled 183 to the PIC using the precision 3-axis stages (< 100 nm alignment tolerance). A power meter 184 (Keysight, N7744A) with a dynamic range of 65 dB was used to analyze the transmitted signal.



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Fig. 5 Setup used to measure the transmission spectrum.

# 187 5. Device Characterization

188 The transmission response of each output channel of the RDL-AWGs was measured using the

189 measurement setup described in Section 4 and shown in Fig. 5. The overall throughput of the

two RDL-AWGs is plotted as a function of wavelength in Fig. 6.



Fig. 6 Transmission spectra of RDL-AWGs. (a), (b): RDL-AWG #1 with a targeted R of
30,000. (c), (d): RDL-AWG #2 with a targeted R of 120,000.

195 For the RDL-AWG #1 with a targeted R of 30,000, shown at Fig. 6 (a) and (b), the 196 throughput is measured to be -4.2 dB in the wavelength bandwidth of 1575 - 1580 nm. We 197 measure a FSR of 0.8 nm and a crosstalk of ~16 dB. The channel spacing between output 198 channels is measured to be 0.1 nm, and the 3-dB transmission bandwidth is 56 pm, 199 corresponding to a resolving power of 28,000 at 1580 nm. With the capability to fabricate the 200 device in a compact area  $(0.9 \times 2.9 \text{ mm}^2)$  and with ultra-low-loss waveguide (<0.02 dB/cm) [25,26], we therefore achieve a resolving power that is in good agreement with the 201 202 theoretical value. Note that the throughput can even be increased by using high coupling 203 efficiency fiber-to-waveguide couplers [27] with mode-matching ultra-high numerical aperture 204 (UHNA) fibers or lensed fibers.

205 Figs. 6 (c) and (d) show the transmission response for the RDL-AWG #2 with a targeted R 206 of 120,000. The throughput is measured to be -11.8 dB, which is 7.6 dB lower than that of 207 RDL-AWG #1. We also see that the crosstalk is ~5.3 dB, which is also poorer than that of RDL-208 AWG #1. The degradation of both throughput and crosstalk are mostly due to the phase errors 209 introduced by the fabrication process in a larger area  $(4.2 \times 2.9 \text{ mm}^2)$ , which depends on the 210 stability of the fabrication process across the dispersive area of the device. The small footprint 211 RDL-AWG device helps to minimize phase errors. In the future, better process control can 212 alleviate this issue further. As a result, the measured resolving power of RDL-AWG #2 is 213 95,000, in contrast to the targeted value of 120,000.

### 214 6. Discussion and Conclusion

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215 The innovative RDL-AWG design presented in this work has unique advantages over traditional AWGs for achieving a high resolving power. An array of directional couplers is 216 217 calculated and optimized to distribute the input signal from the delay line into the free 218 propagation region. By making the AWGs more compact, it significantly reduces the impact of fabrication imperfections and uniformity issues, which limit the traditional AWGs from 219 220 achieving ultra-high resolving powers. The design theory is discussed in detail. We also 221 experimentally demonstrate devices with resolving powers of 28,000 and 95,000. These 222 devices are more than 100 times more compact compared to the traditional AWGs.

223 The presented preliminary RDL-AWGs have only 20 arrayed waveguides and 8 output 224 channels. The experimental results show that the concept to reuse the delay line to reduce the 225 footprint works well. The next step is to build an RDL-AWG with a larger number of arrayed 226 waveguides and output channels, which means a higher FSR. A challenge to note is the loss 227 due to the DCs. As the number of arrayed waveguides in the RDL-AWG increases, the number 228 of arrayed DCs also increases accordingly. For example, if the loss of a single DC is estimated 229 to be 0.01 dB, for a 20-waveguide RDL-AWG, the estimated loss due to arrayed DCs will be 230 0.095 dB. For a 100-waveguide RDL-AWG, the loss will be 0.489 dB. This is an extra source 231 of loss which does not exist in traditional AWGs. Careful engineering and optimization of the 232 DCs are required in future developments.

In this paper, we demonstrated the RDL-AWGs on a 300-nm thick Si<sub>3</sub>N<sub>4</sub> core layer. It provides a lower bending loss compared to other waveguide geometries that have relatively lower confinement factors. This in turn makes it possible to design RDL-AWGs with smaller footprints, which are less susceptible to fabrication variations. To further reduce the minimum bending radii, a thicker Si<sub>3</sub>N<sub>4</sub> core layer can be used [21], which makes the RDL-AWG a more compelling approach for compact higher-resolution spectrometers.

The power and phase distribution can be arbitrarily generated by the arrayed DCs. This means that the output spectrum can be altered to achieve various peak profiles. Besides the traditional Gaussian, a flat-top shape is one of the preferred options [24].

As discussed in Section 5, by comparing the performance of the two RDL-AWG designs presented in this paper, the design with higher R starts to be affected by phase errors due to a larger footprint. This phenomenon is similar to the performance degradation of traditional AWGs fabricated on the 300-nm  $Si_3N_4/SiO_2$  platform, when the resolving power is larger than 10,000. For the higher-R designs, a delay line that fits in a more compact area is required. We are currently working on a new structure that utilizes an array of spiral delay lines. It has the potential to further reduce the size of the RDL-AWG with R>100,000 by a factor of 5.

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- 259

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